

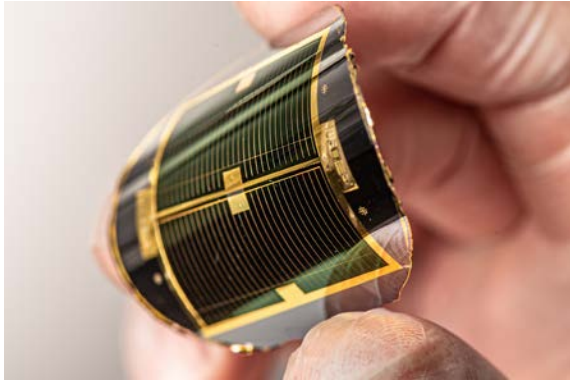
Remote epitaxy of III-V solar cells via hydride vapor phase epitaxy

Dennice Roberts¹, Hyunseok Kim², Elisabeth McClure¹, Anna Braun¹, Kevin Schulte¹, Aaron Ptak¹, Jeehwan Kim², John Simon¹

¹*National Renewable Energy Laboratory*

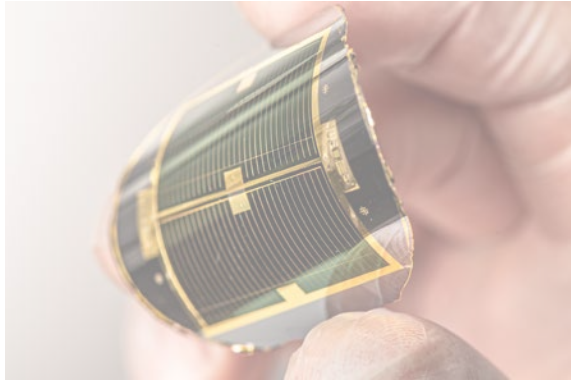
²*Massachusetts Institute of Technology*

Advantages of III-V solar



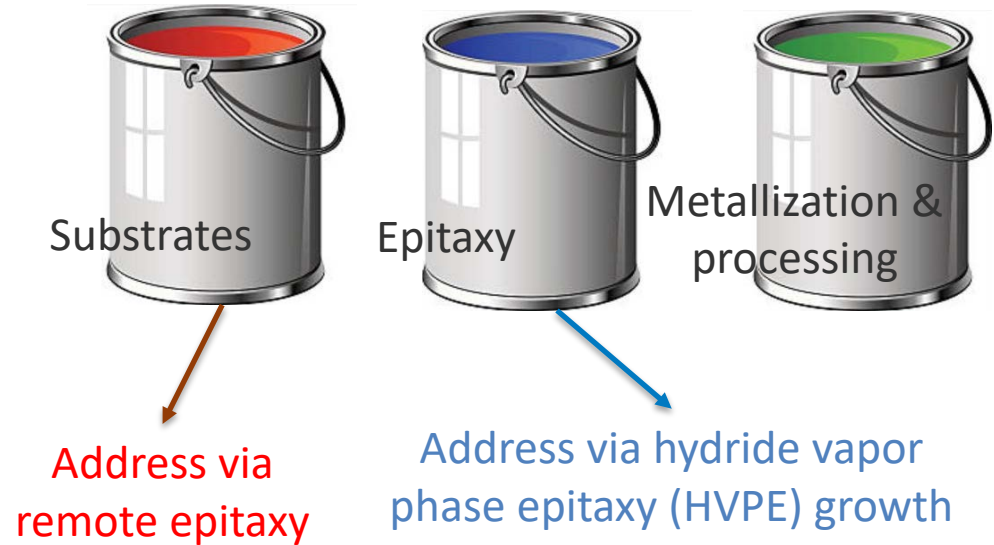
- Record efficiencies
 - 29.1% single junction GaAs (one-sun)
 - 47.1% multijunction (concentrated)
- Thin, flexible, radiation hard – robust in harsh environments

Advantages of III-V solar

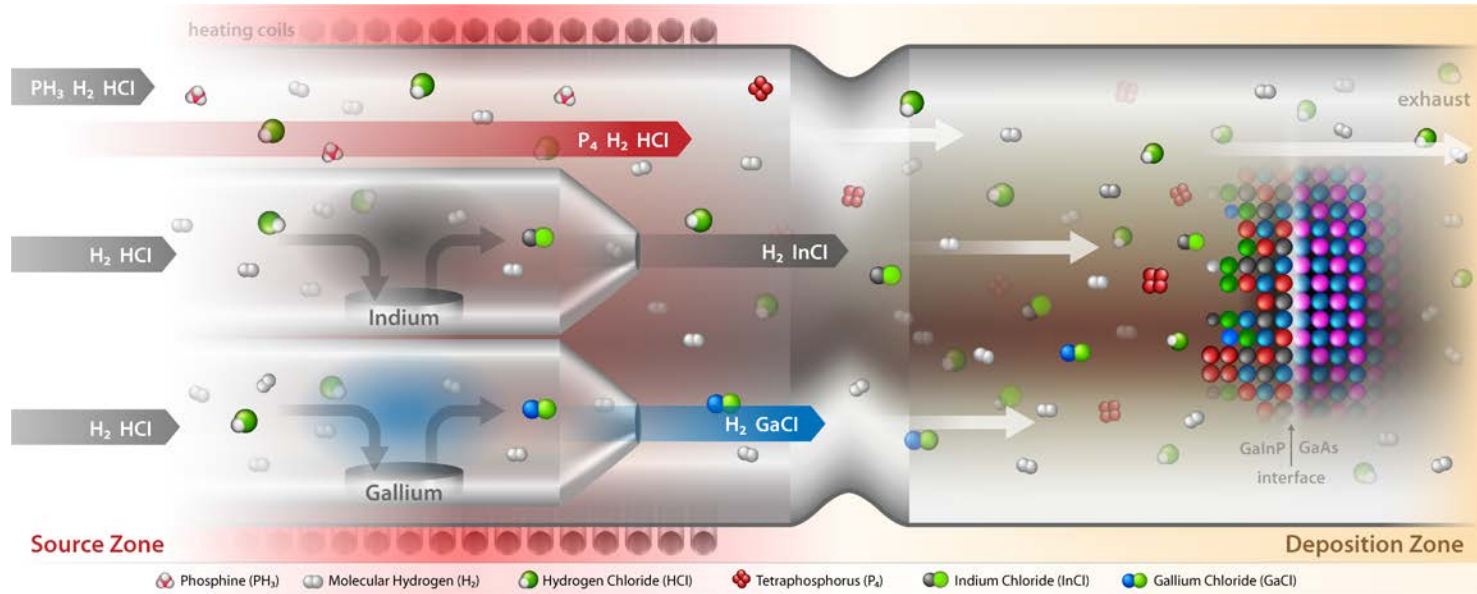


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 - 29.1% single junction GaAs (one-sun)
 - 47.1% multijunction (concentrated)
- Thin, flexible, radiation hard – robust in harsh environments

Major costs in III-V solar:

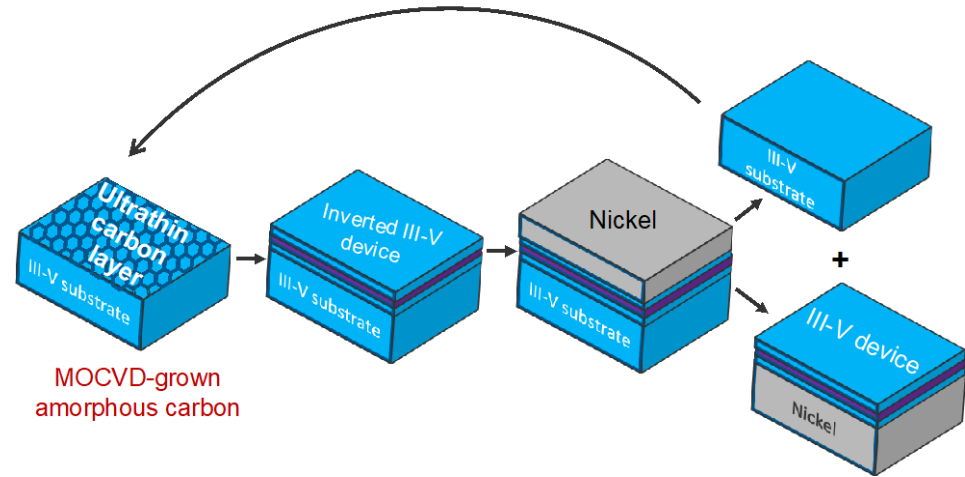
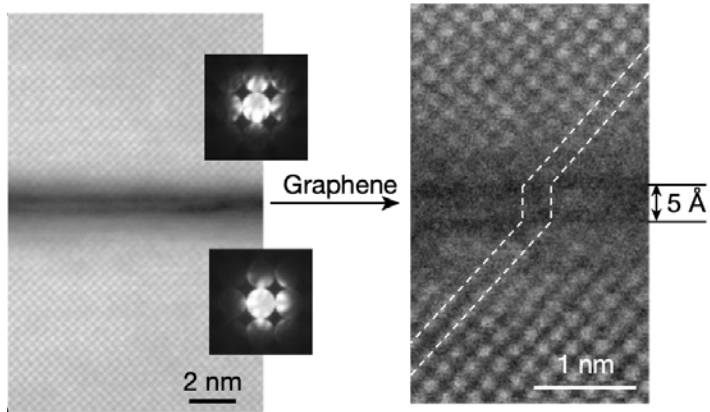


Hydride vapor phase epitaxy (HVPE) growth



- Atmospheric pressure process
- Less expensive precursors than incumbent OMVPE growth method
- Higher precursor utilization
- Extremely fast growth rates up to $528 \mu\text{m/h}$

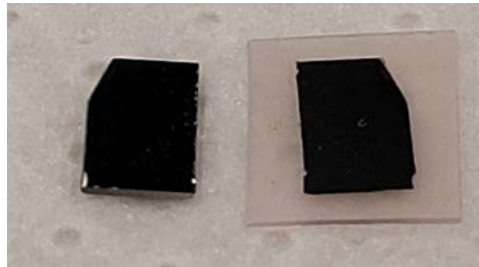
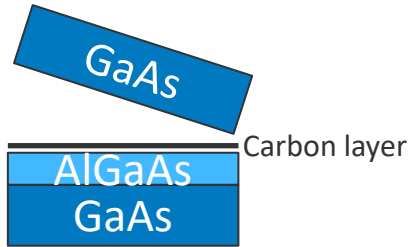
Combining HVPE growth and remote epitaxy



Remote epitaxy of GaAs on GaAs
demonstrated by MOCVD

For more on 2D layer fabrication and optimization, check out talks by Jeehwan Kim and Hyunseok Kim in this session

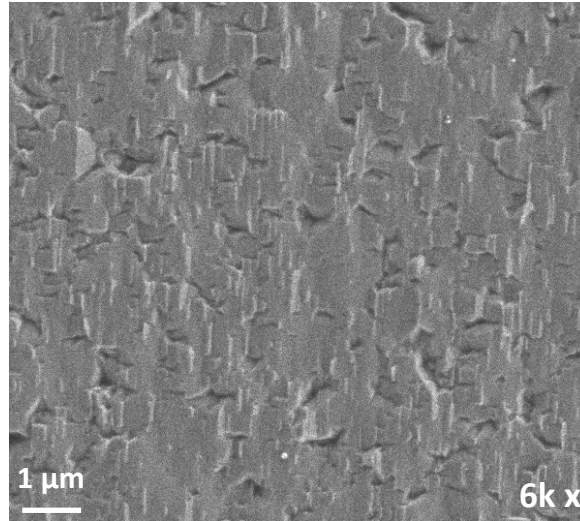
Exfoliation of HVPE-grown GaAs layer



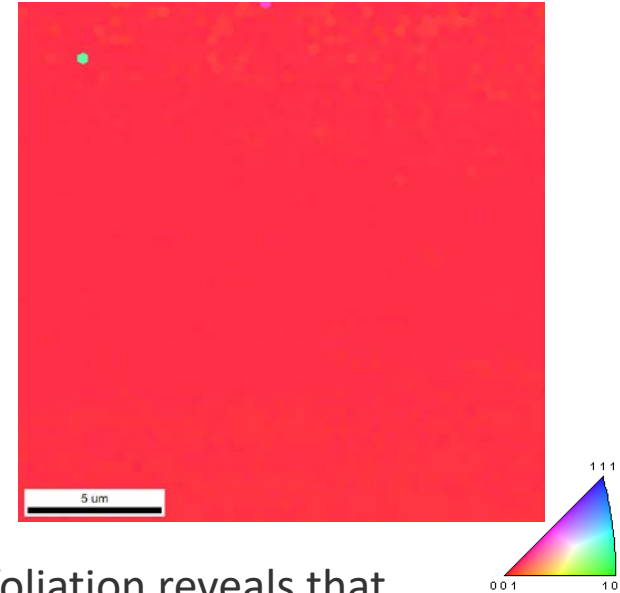
Substrate

Released
GaAs layer

SEM of top surface, pre-exfoliation

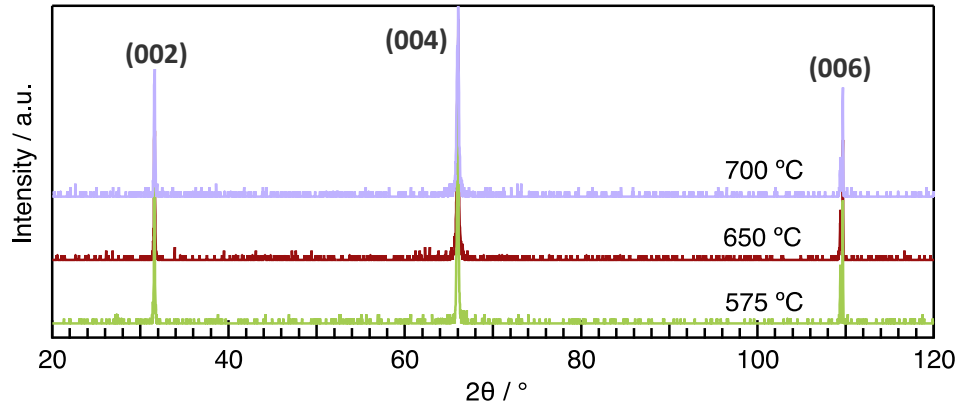
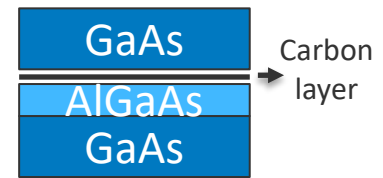


EBSD map, layer at wafer interface



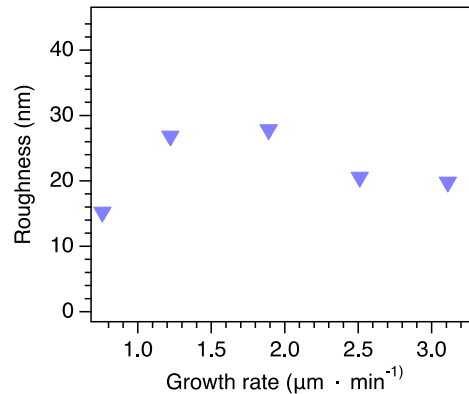
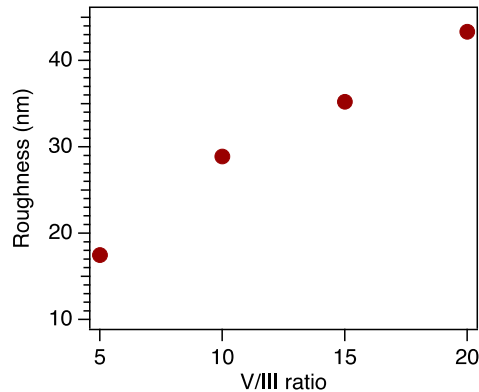
Despite rough surface, exfoliation reveals that all nucleation proceeded along (001) face

Nucleation of GaAs on amorphous carbon



Single crystal films oriented along (001) at temperatures between 575 and 700 °C

**650 °C, V/III = 5,
growth rate = 0.76 $\mu\text{m}/\text{min}$**

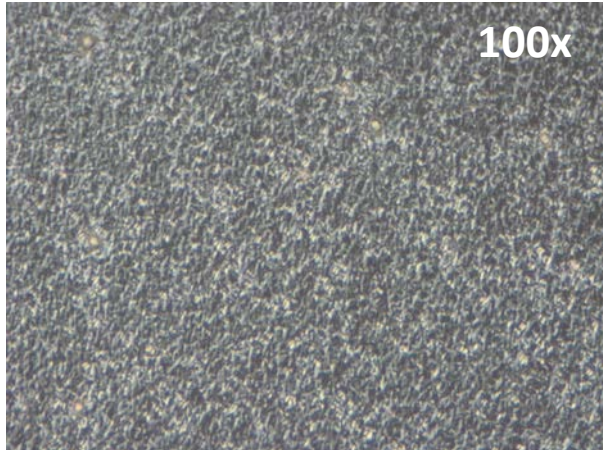


Among coalesced films: film roughness has dependence on V/III, some dependence on GR

Planarizing film surfaces

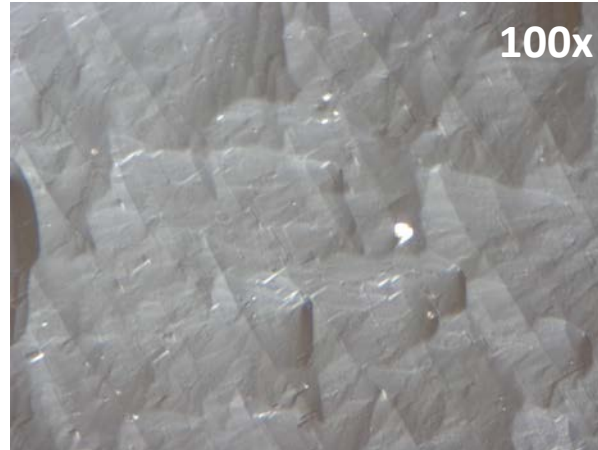
Improve surface morphology and reduce roughness by introducing layer with high carrier flow and high GaCl generation

500 nm nucleation under N_2



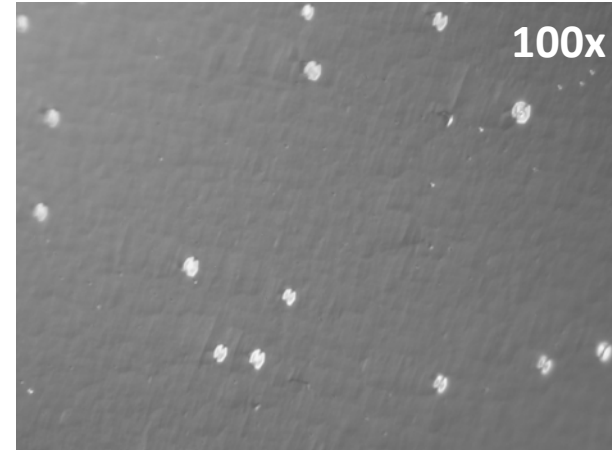
$R_a = 15.2 \text{ nm}$

500 nm under N_2 + 3 μm high
flow layer under H_2



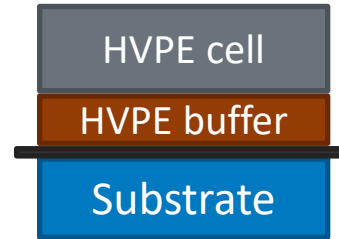
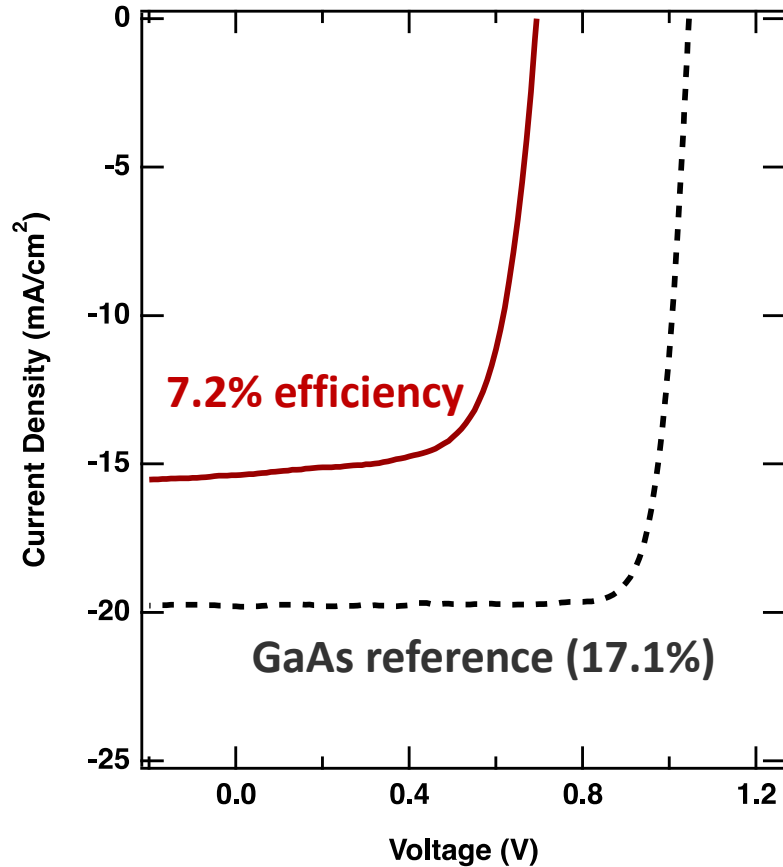
$R_a = 10.6 \text{ nm}$

3 μm high flow layer under N_2

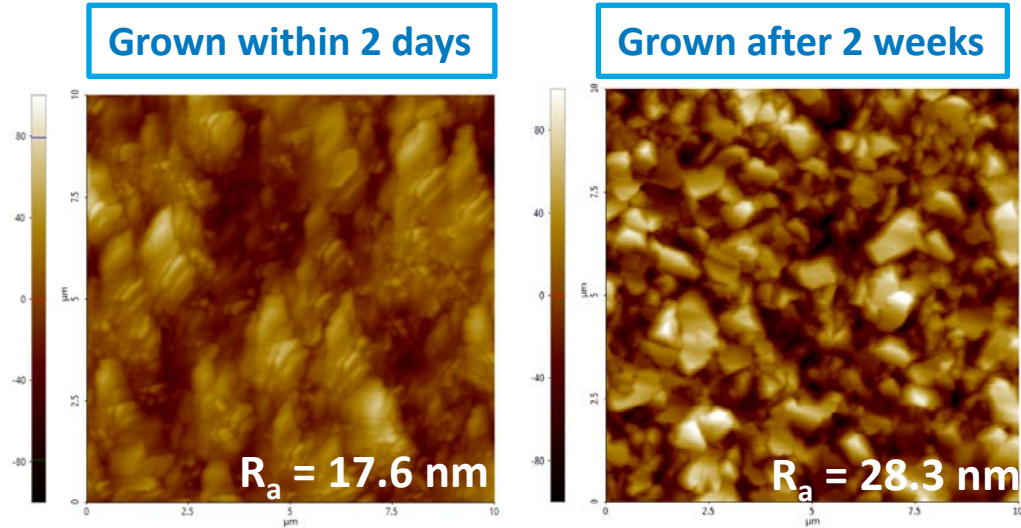
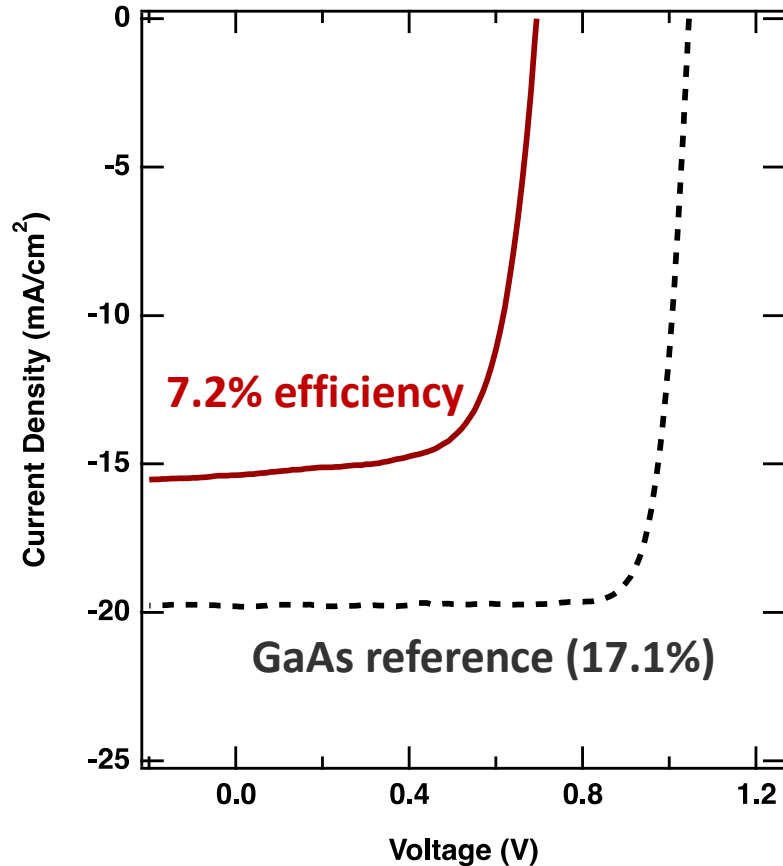


$R_a = 2.2 \text{ nm}$

Growth of III-V solar cells

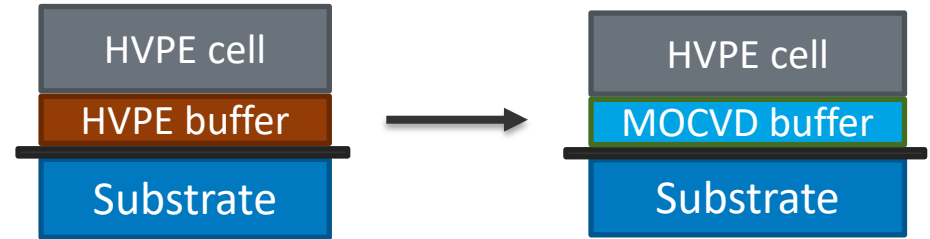
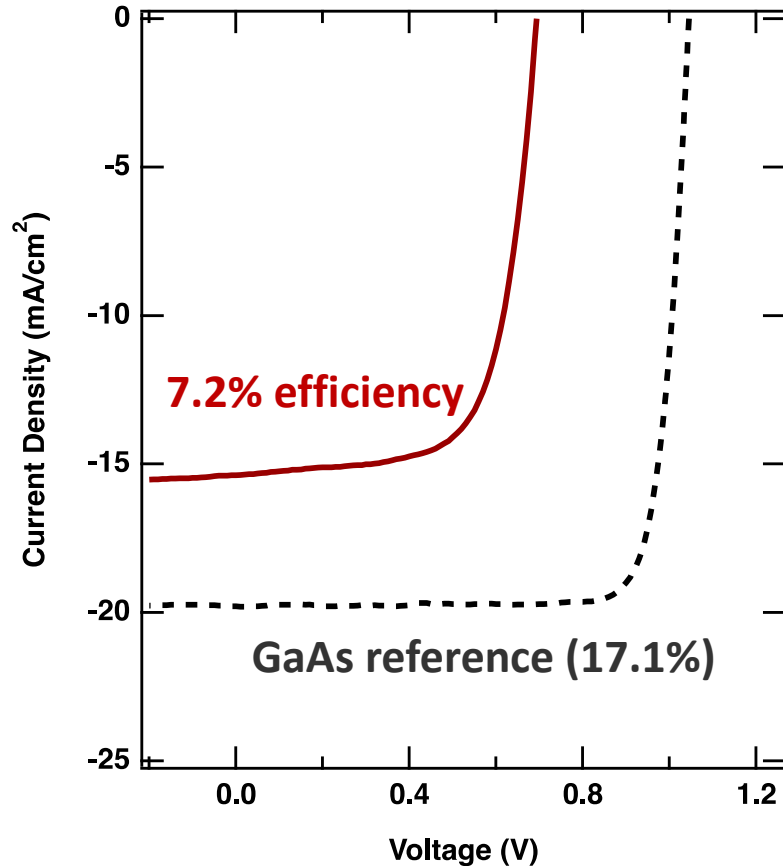


Growth of III-V solar cells



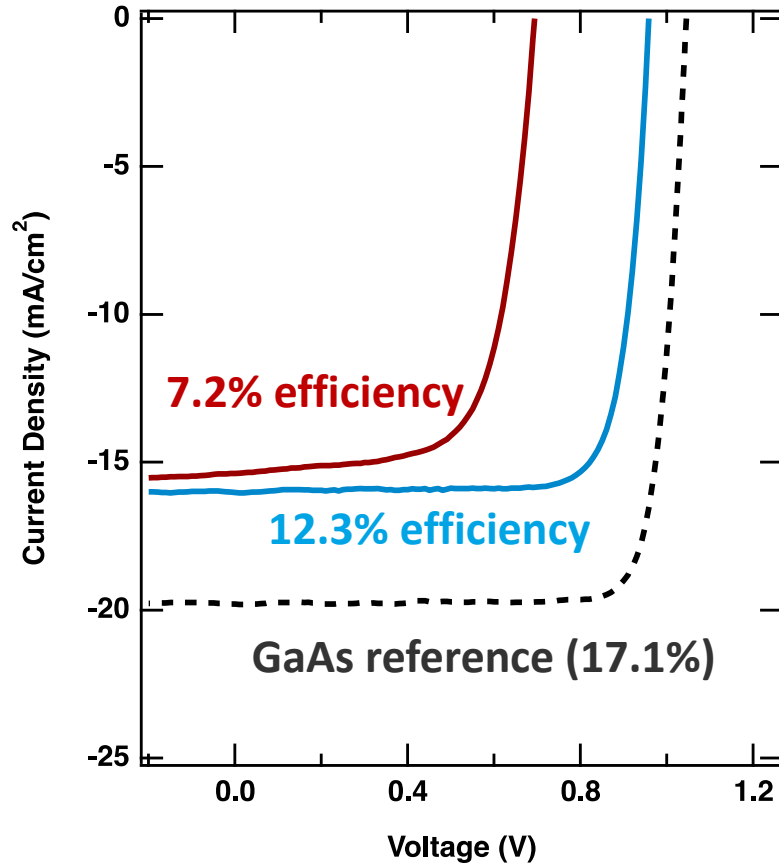
Surface degradation of carbon substrates over time results in increased film roughness and regions of no growth

Growth of III-V solar cells



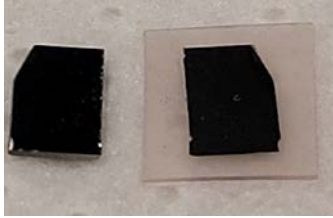
To negate the effects of surface degradation, MOCVD buffer is grown before shipping to NREL

Growth of III-V solar cells



- Cell efficiency of 7.2% for all-HVPE grown cell
- Using MOCVD-grown buffer to offset carbon degradation, see cell with 12.3% efficiency
- After applying anti-reflective coating, cell efficiency is >19%!

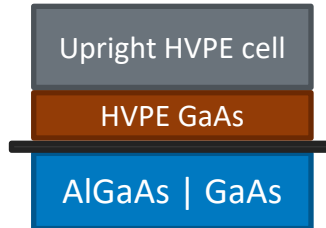
Conclusions



Investigated conditions for remote epitaxy of GaAs on amorphous carbon layer via HVPE and show proof of exfoliation



Explored planarization conditions to improve film surface and morphology



Developed remote-epitaxial GaAs cell with promising path for substantial improvements

Thank you!

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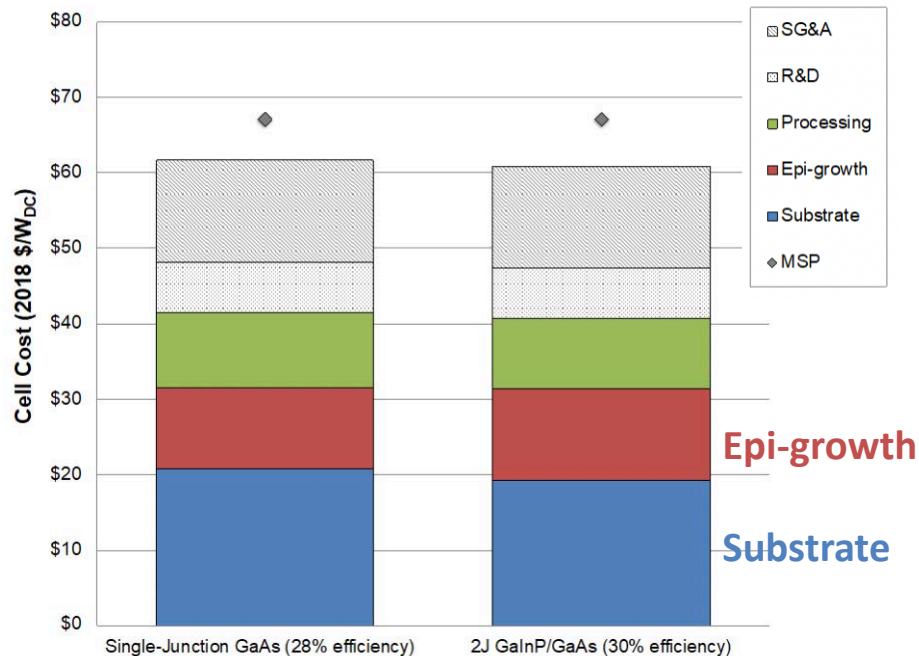
dennice.roberts@nrel.gov

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This work was authored in part by the National Renewable Energy Laboratory, operated by Alliance for Sustainable Energy, LLC, for the U.S. Department of Energy (DOE) under Contract No. DE-AC36-08GO28308. Funding provided by DOE's Office of Energy Efficiency and Renewable Energy (EERE) under Solar Energy Technologies Office (SETO) Agreement No. 35365. The views expressed in the article do not necessarily represent the views of the DOE or the U.S. Government. The U.S. Government retains and the publisher, by accepting the article for publication, acknowledges that the U.S. Government retains a nonexclusive, paid-up, irrevocable, worldwide license to publish or reproduce the published form of this work, or allow others to do so, for U.S. Government purposes.



Large-scale deployment of III-V solar limited by cost



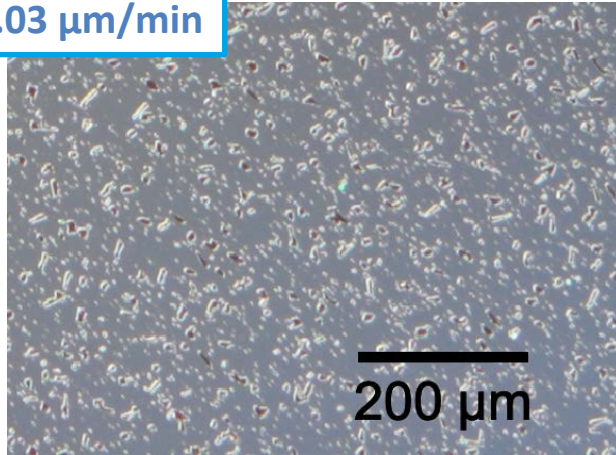
Cost breakdown for III-V cells by OMVPE

Nucleation of GaAs on amorphous carbon

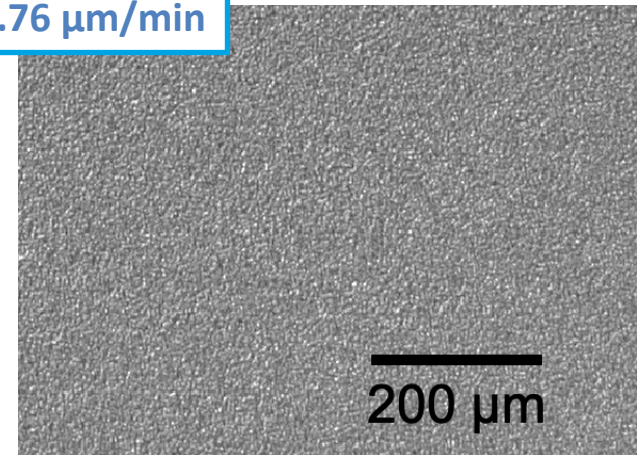


Carbon layer

.03 $\mu\text{m}/\text{min}$



.76 $\mu\text{m}/\text{min}$



Island growth at very slow growth rates; coalesced films at higher GRs